

PATENT ABSTRACTS OF JAPAN

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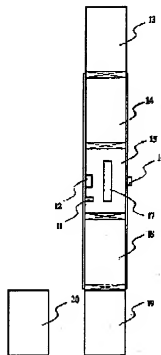
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(54) INLINE SPUTTERING DEVICE

(57)Abstract:

PURPOSE: To provide the inline sputtering device having excellent productivity by providing a means for measuring the rotating speeds of pallets carrying substrates to be formed with films and a means for accumulating the measured values thereof for each of carriers.

CONSTITUTION: This inline sputtering device is provided with a chamber group which has at least a loading chamber 14 for loading the substrates to be formed with the films, a sputtering chamber a15 for forming the films by sputtering on the substrates to be formed with the films and an unloading chamber 18 for unloading these substrates, the carriers a17 which have the pallets carrying the substrates to be formed with the films and move between the respective chambers of the chamber group and a rotational driving device 16 for the pallets which is mounted on the carriers a17 and moves the pallets of the carriers a17 while rotating the pallet. The respective carriers are identified by a carrier identifying mechanism 12 of the sputtering chamber a15 and the rotating speeds of the pallets carrying the substrates to be formed with the films are measured by a mechanism 11 for measuring the rotating speeds of the pallets. The measured values are accumulated for each of the carriers by a control panel 20.



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